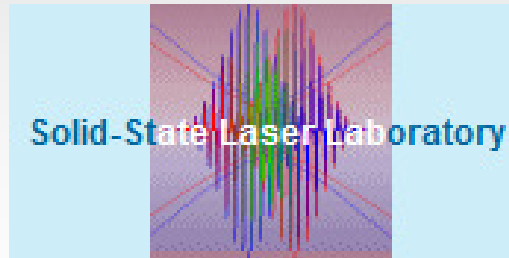


# ***2D and 3D Geometries produced by Ultrashort Laser Pulses***

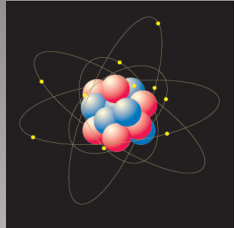
**Marian Zamfirescu**

INFLPR, Bucharest, Romania

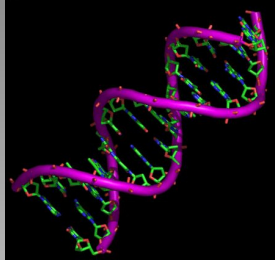


<http://sll.inflpr.ro>

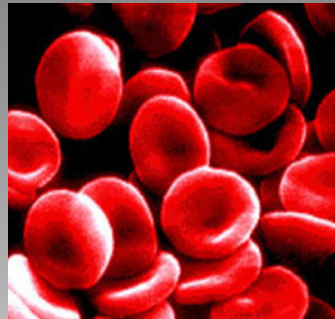
**Atoms**



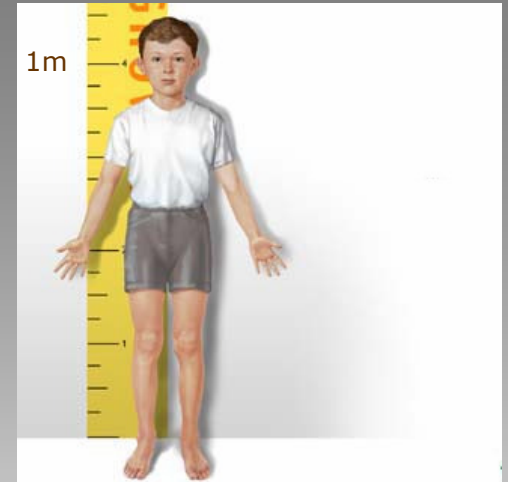
**Molecules**



**Cells**



**Insects**



**Angstrom**  
 $10^{-10}$

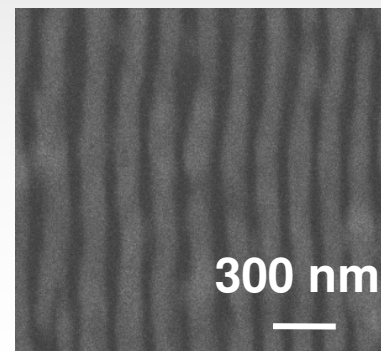
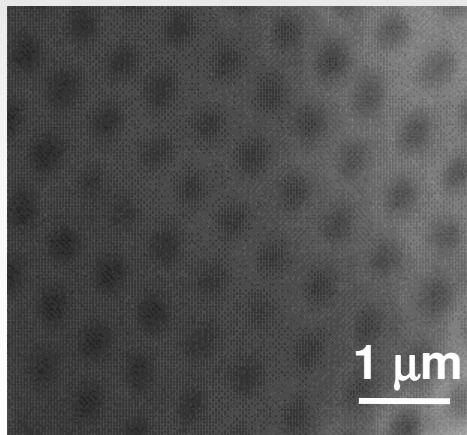
**Nanometer**  
 $10^{-9}$

**Micrometer**  
 $10^{-6}$

**Millimeter**  
 $10^{-3}$

**Meter**

Nanostructures produced by laser



# Lasers with high power and ultrashort pulse duration

Light bulb



Watt  
1 W

CO<sub>2</sub> Laser



Kilo Watt  
10<sup>3</sup> W

Hydroelectric Power Station



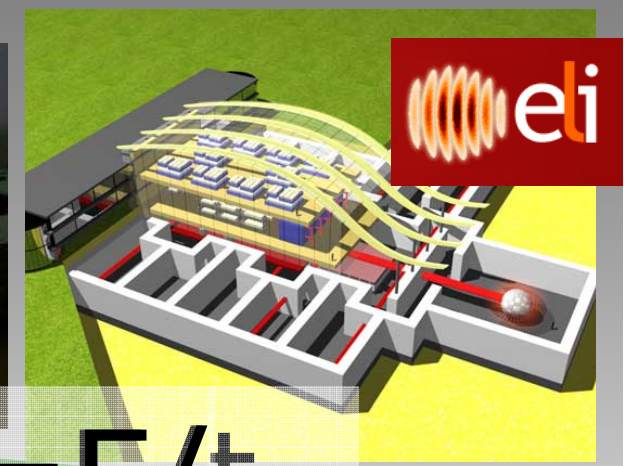
Giga Watt  
10<sup>9</sup> W

TEWALAS Laser at INFLPR



Tera Watt  
10<sup>12</sup> W

Extreme light Infrastructure



Peta Watt  
10<sup>15</sup> W

$$P = E / t$$

Chronometer



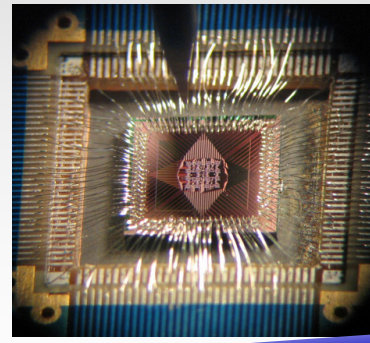
Seconds

High speed photography



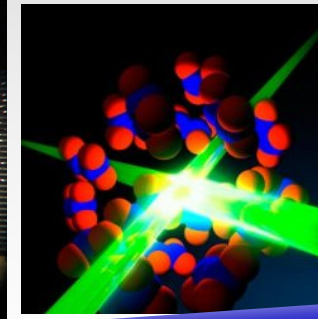
Milliseconds  
10<sup>-3</sup>

Processor's clock time



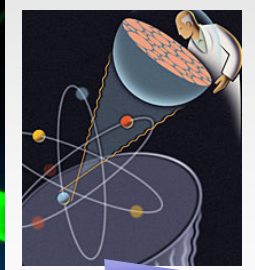
Nanoseconds  
10<sup>-9</sup>

Chemical reactions



Femtoseconds  
10<sup>-15</sup>

Electrons movement



Attoseconds  
10<sup>-18</sup>

# Applications of femtosecond lasers

## Low pulse energy (nJ)

- Dynamics of chemical reactions;
- High resolution laser scanning microscopy.

## Medium pulse energy (mJ)

- laser microprocessing: laser ablation or photo-induced chemical reactions (material modification by nonlinear absorption);
- generation of THz radiation.

## Ultra intense laser beams (J)

- accelerated electron, X-Rays (TW lasers);
- protons beams, accelerated ions, Gamma rays (PW lasers)

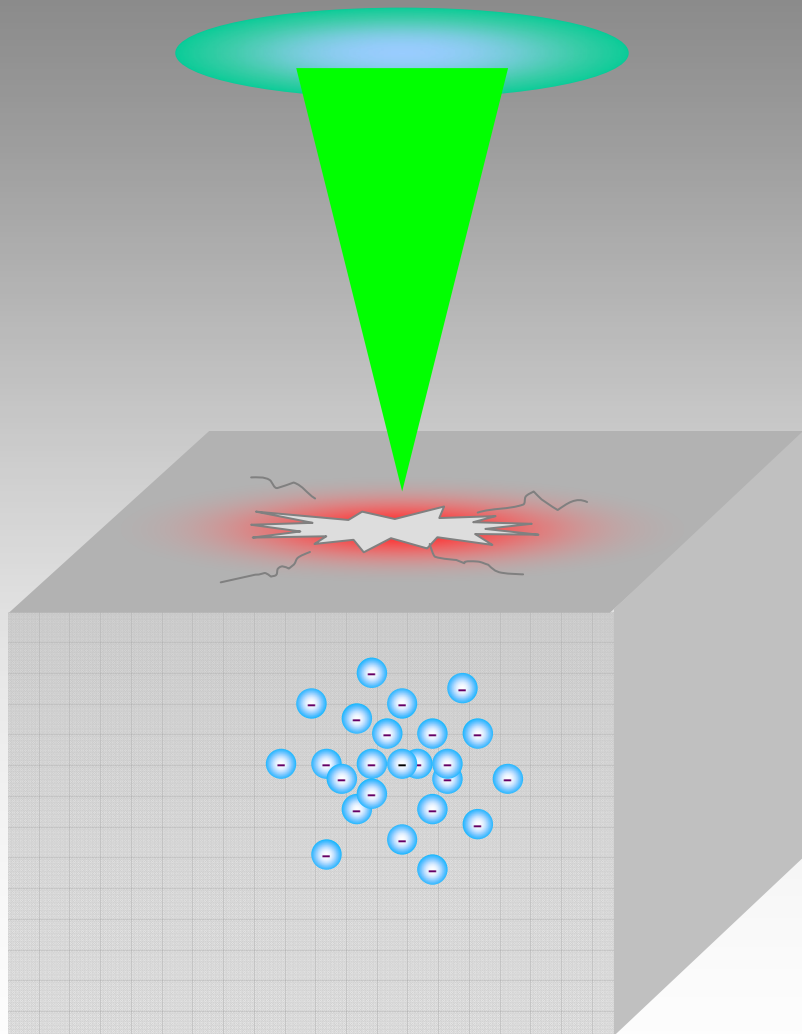


## Microprocessing techniques with ultrashort lasers pulses

- **Laser ablation with sub-micrometer resolution**
- **Two-Photon Photopolymerization (TPP)**
- **Near-field laser lithography**
- **Laser Induced Forward Transfer (LIFT)**
- **Two-Photons Excited Spectroscopy (TPE)**

# Interaction of materials with intense laser beam

Long laser pulses (ns)



- Focused laser beam create free electrons in the irradiated material.

$$h\nu = E_g - \text{linear absorption}$$

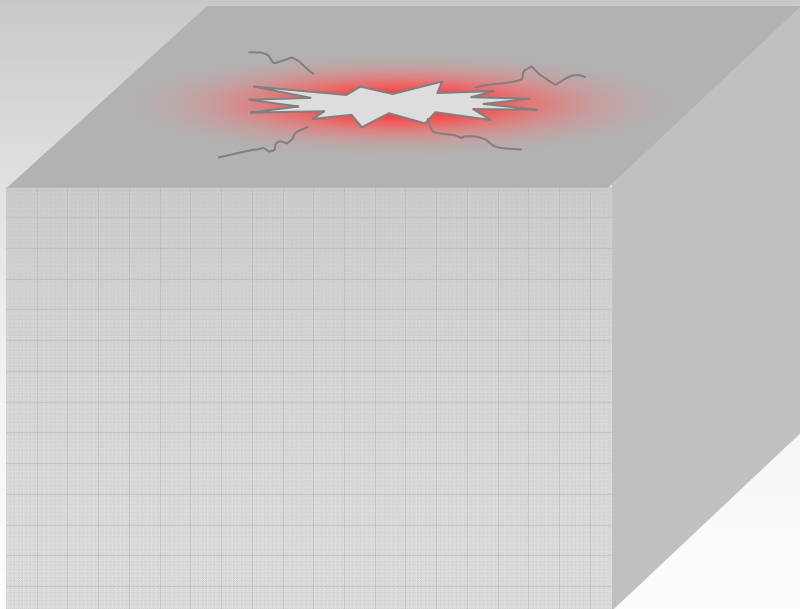
$$N \times h\nu = E_g - \text{nonlinear absorption}$$

- The free electrons interact with the crystal lattice heating the irradiated area.
- At laser pulses longer than the thermal diffusion time a large area is heated around the irradiated spot.
- When the temperature of the material reaches the vaporization temperature, the material is locally removed from the target by vaporization.

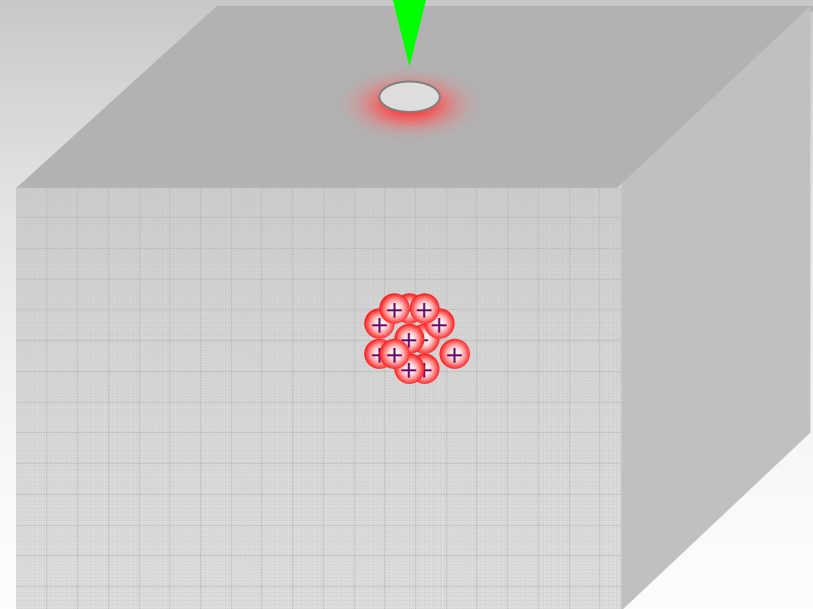
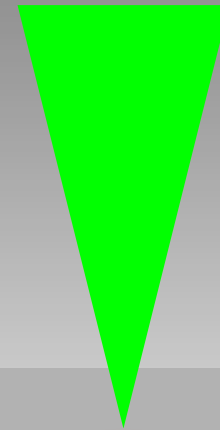
A crater is formed. The adjacent area is thermally affected resulting cracks and debris.

# Interaction of materials with intense laser beam

Long laser pulses (ns)

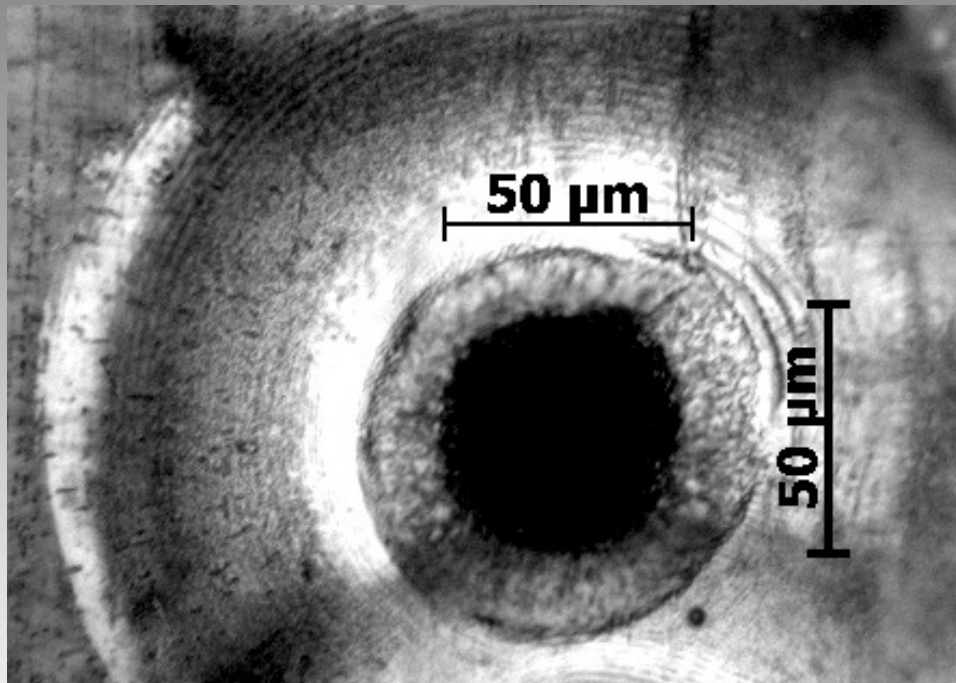


Ultrashort laser pulses (fs)

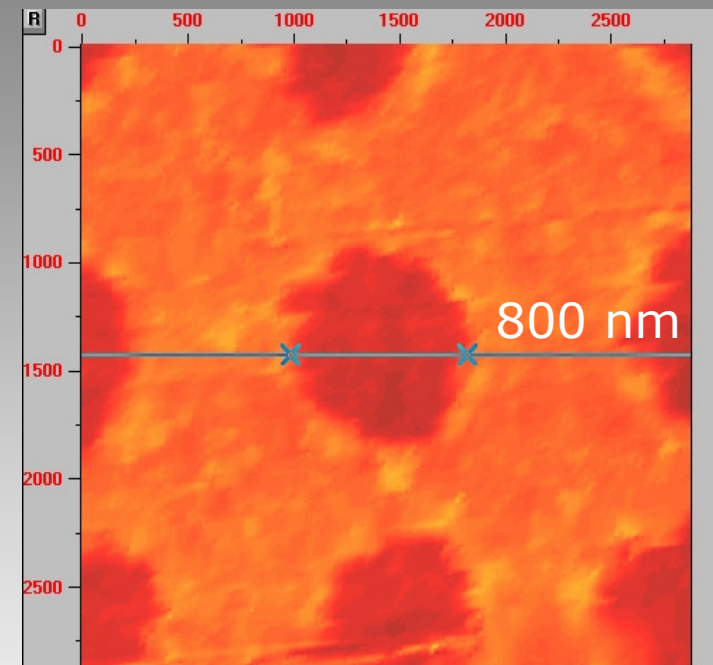


# Nanosecond versus femtosecond laser processing

Laser processing with ns pulses



Laser processing with fs pulses



**Long pulses:** The heat affected zone is much larger than the laser irradiated area.

**Short pulses:** nonlinear absorption in the center of a focalized beam induces material modification at submicrometer size => micro and nanostructuring

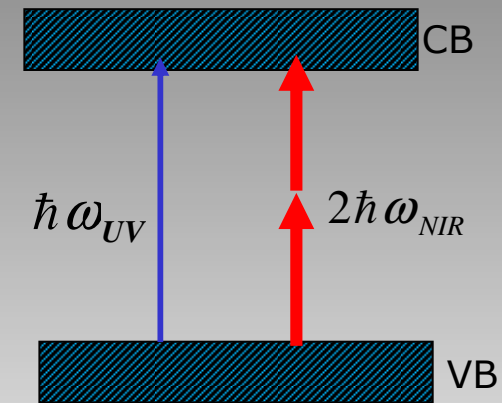
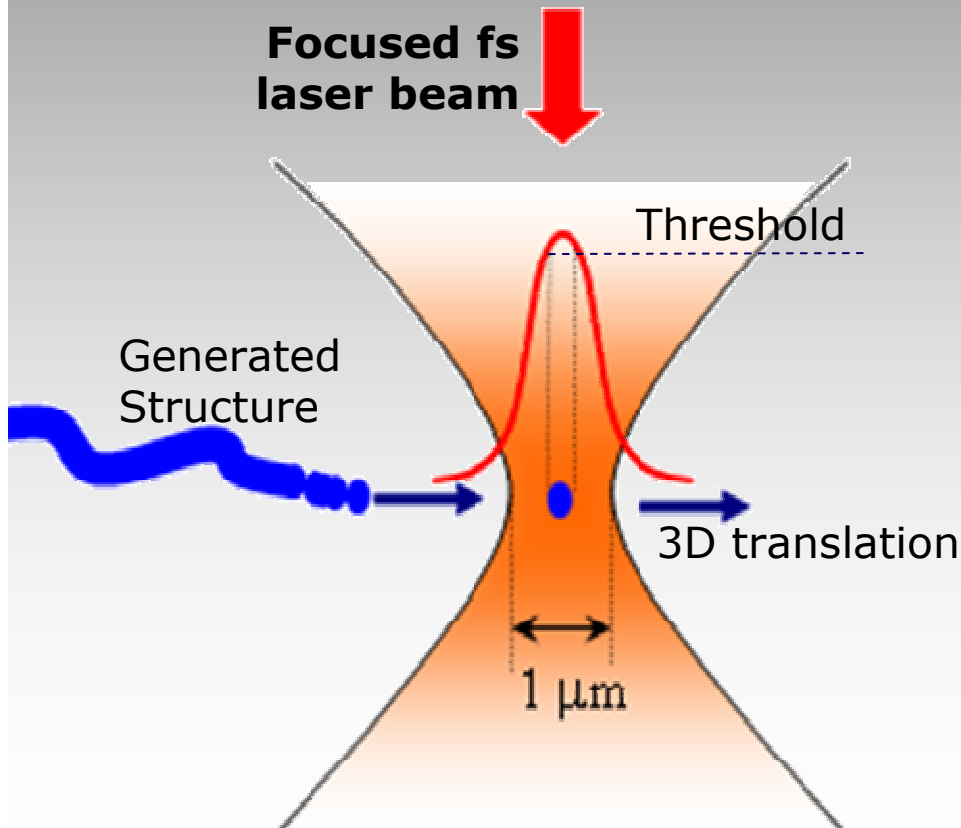


# How to overcome the diffraction limit by a femtosecond laser?

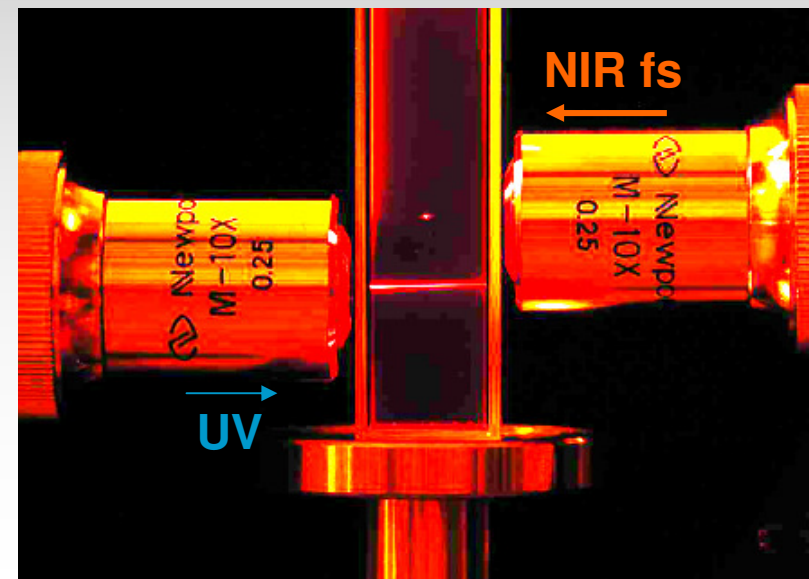
Femtosecond laser beam easily induces nonlinear absorption in the center of a focused spot.

Two-photons or multiphotons absorption:

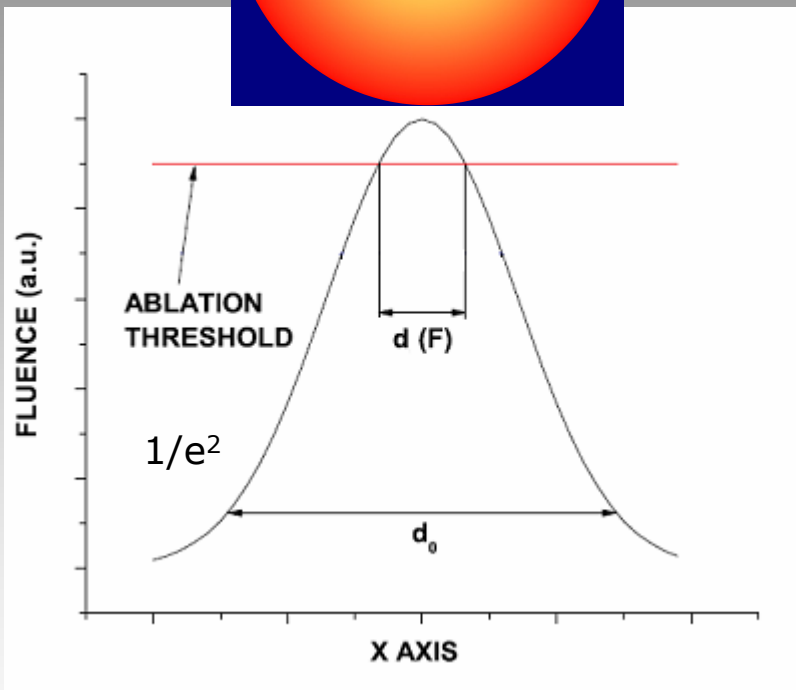
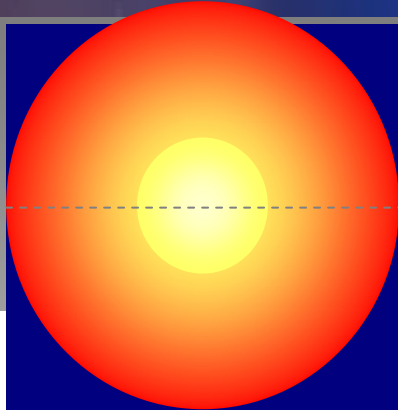
- *photochemical reaction (photopolymerization)*
- *glass densification (waveguide in glasses)*
- *laser ablation*



NIR two-photon vs. UV absorption



# Laser spot diameter vs ablated spot



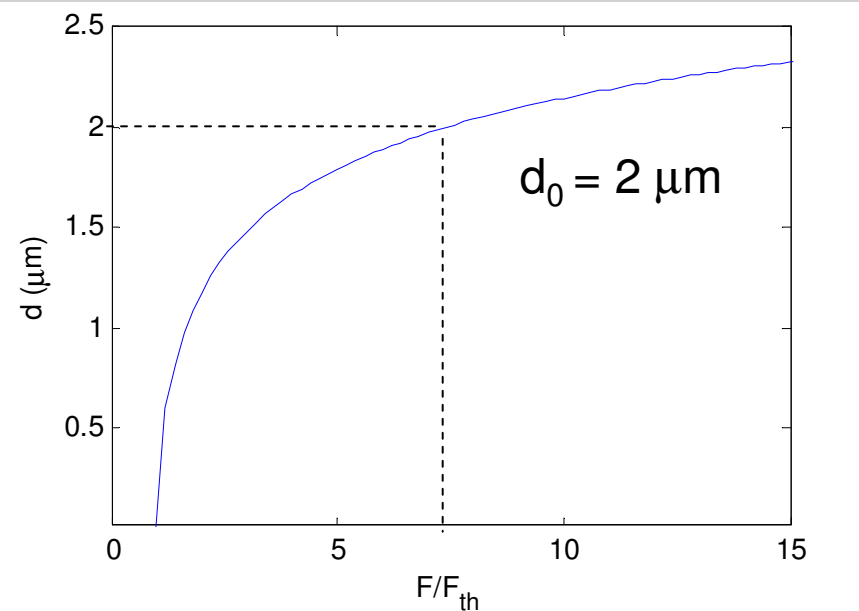
When the laser fluence (intensity) is kept just above the ablation threshold the material will be processed with precision under the diffraction limit.

$$d_0 = \frac{2M^2 \lambda}{\pi NA} \approx \frac{\lambda}{NA}$$

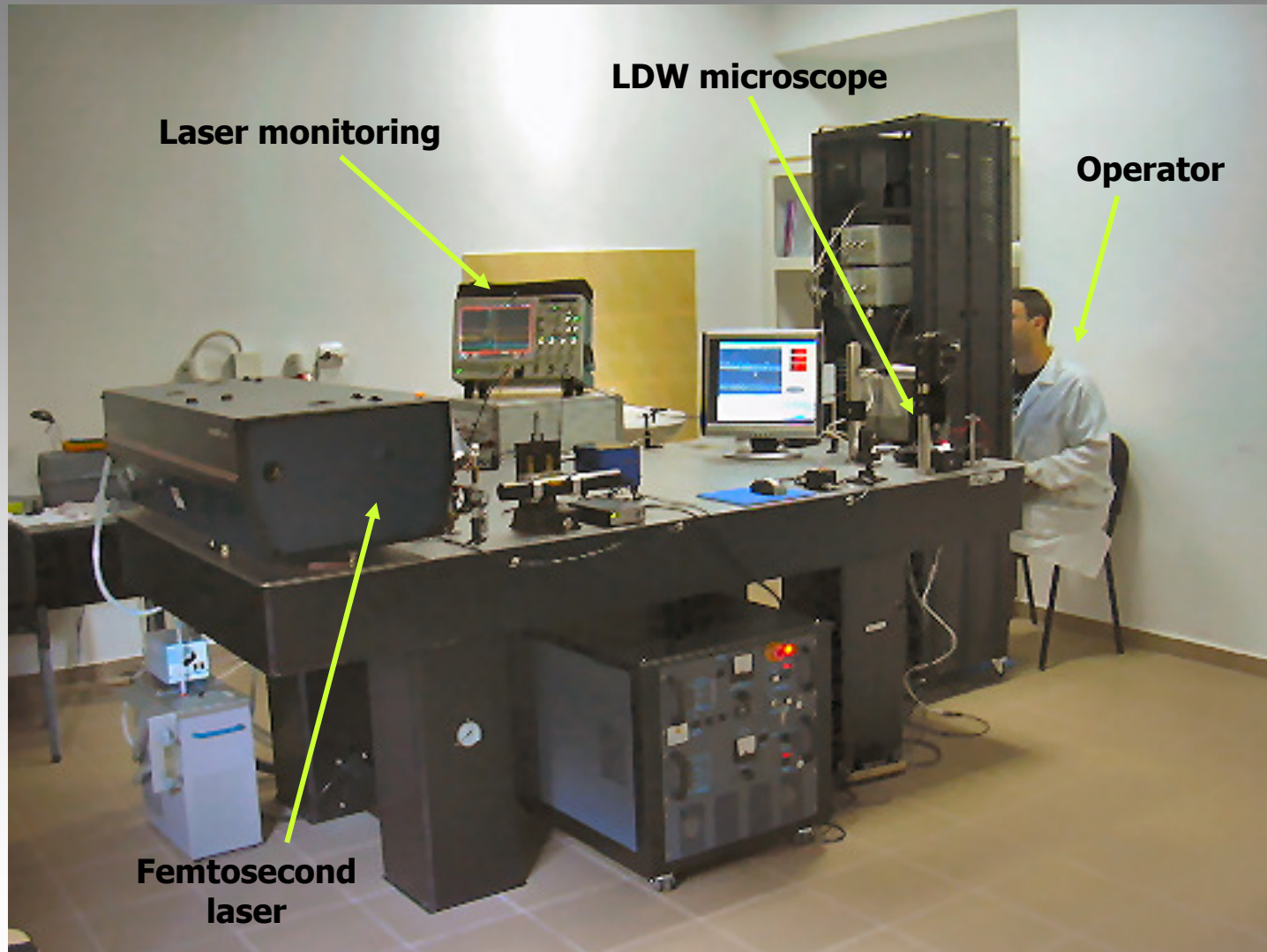
$d_0$  – minimum diameter of the focused laser beam

$NA$  – numerical aperture

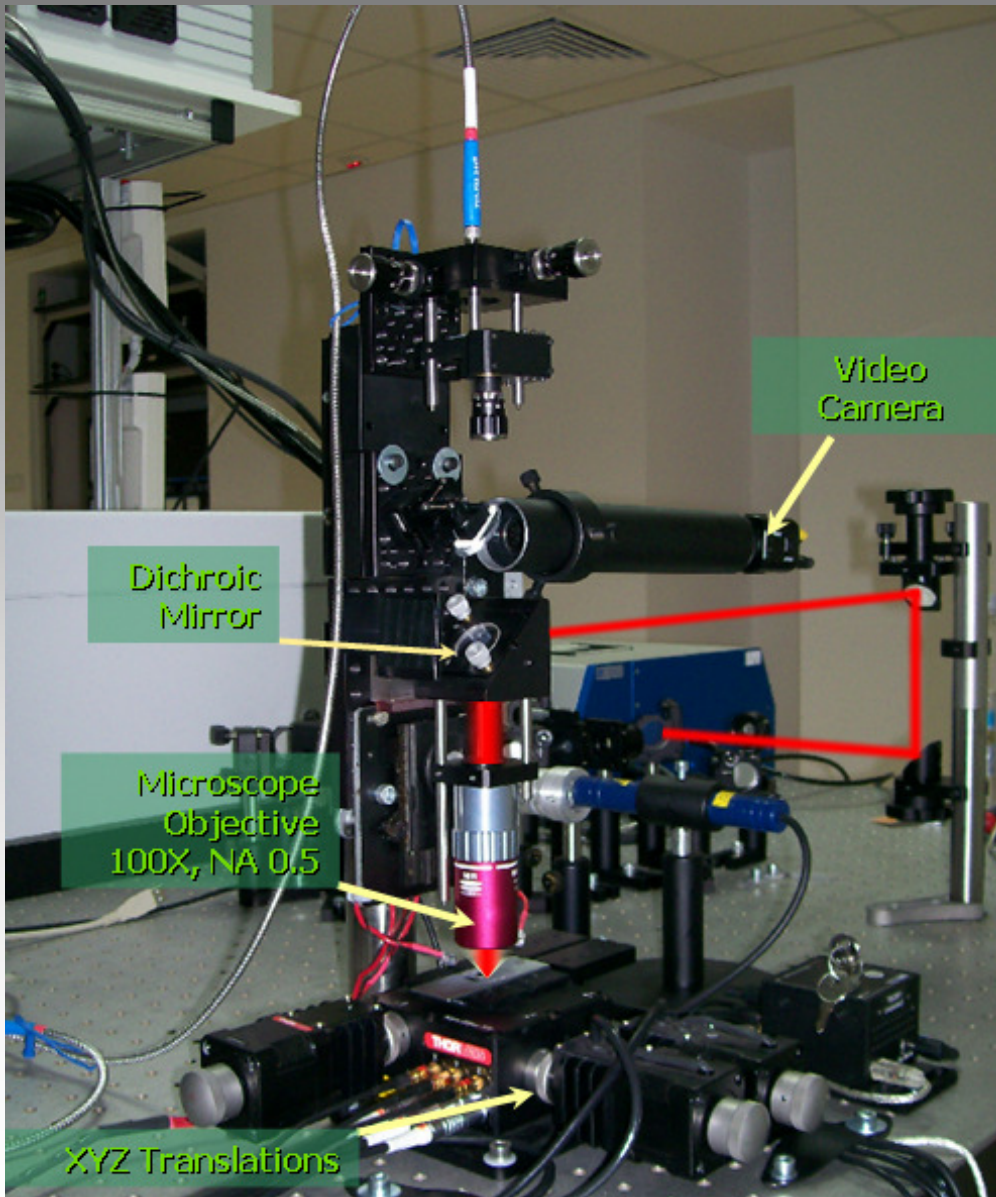
$$d(F) = \frac{d_0}{\sqrt{2}} \sqrt{\ln(F / F_{th})}$$



# Laser Direct-Writing (LDW) with femtosecond laser



# Opto-mechanical system for micro/nano-structuring



## Laser sources

- Clark MXR - CPA2101:  
wavelength 775 nm ,  
pulse duration 200 fs,  
repetition rate 2KHz ;
- Femtolasers – Synergy Pro:  
790 nm, 20 fs, 75 MHz .
- Spectra Physics – Tsunami:  
750-850 nm, 80 fs, 80MHz ;

## Translation system XYZ

- stepper: 4x4x4 mm<sup>3</sup> or 50x50x25 mm<sup>3</sup>.
- precision 400 nm.
- piezo: 20x20x20 μm<sup>3</sup>

## Focusing optics

- 10X to 100X
- NA from 0.2 to 1.4 (immersion oil).

## Visualization

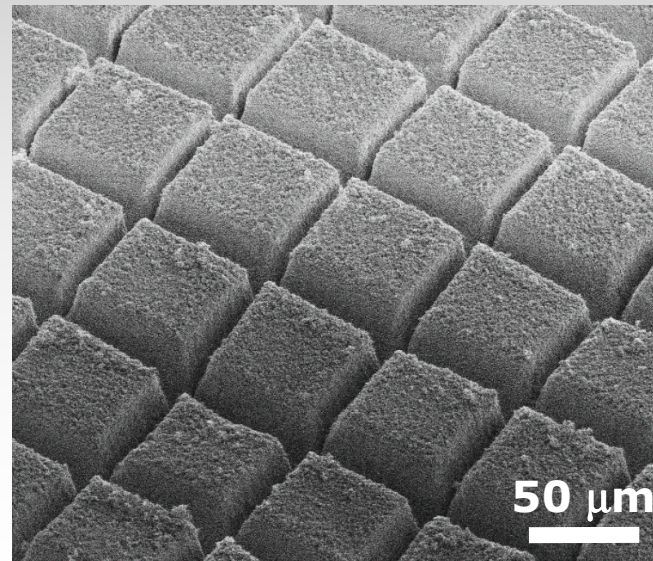
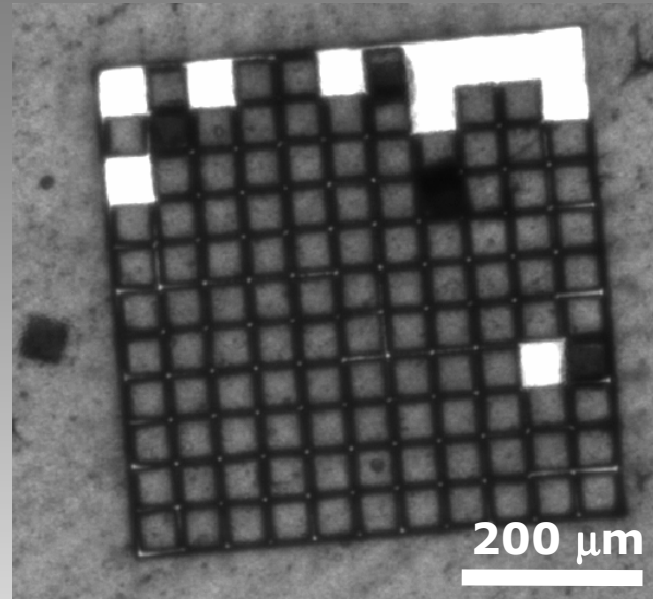
- CCD camera 768 x 494 pixels.
- image rezolution < 1 μm



# Microstructures fabricated by femtosecond laser ablation



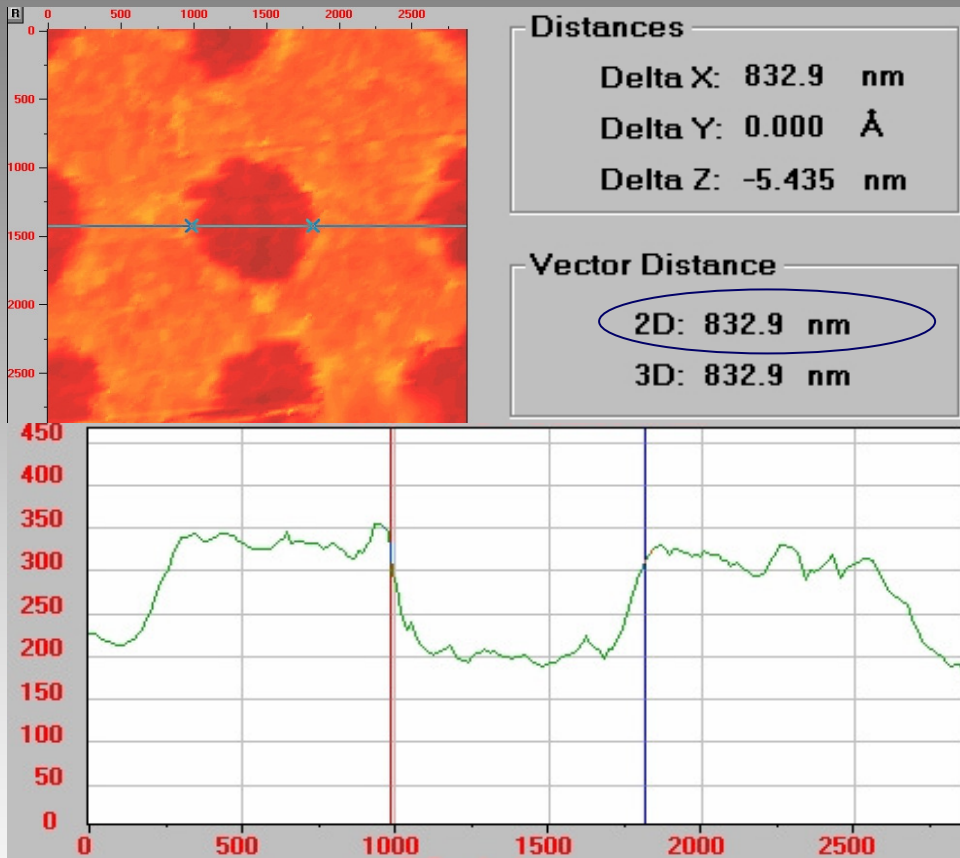
Laser ablation of alumina target  
(100  $\mu\text{m}$  thickness)



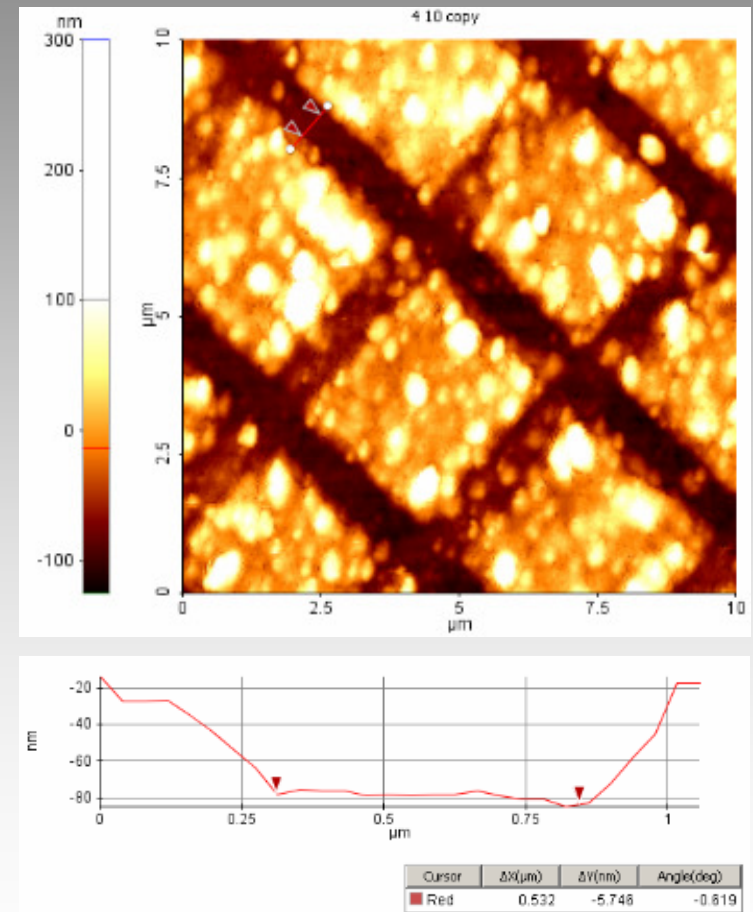


# Laser ablation with sub-micrometer resolution

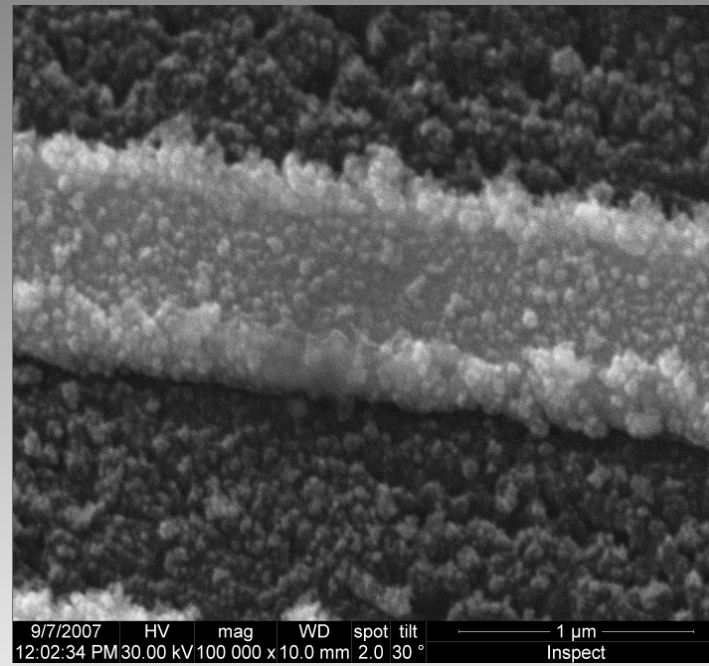
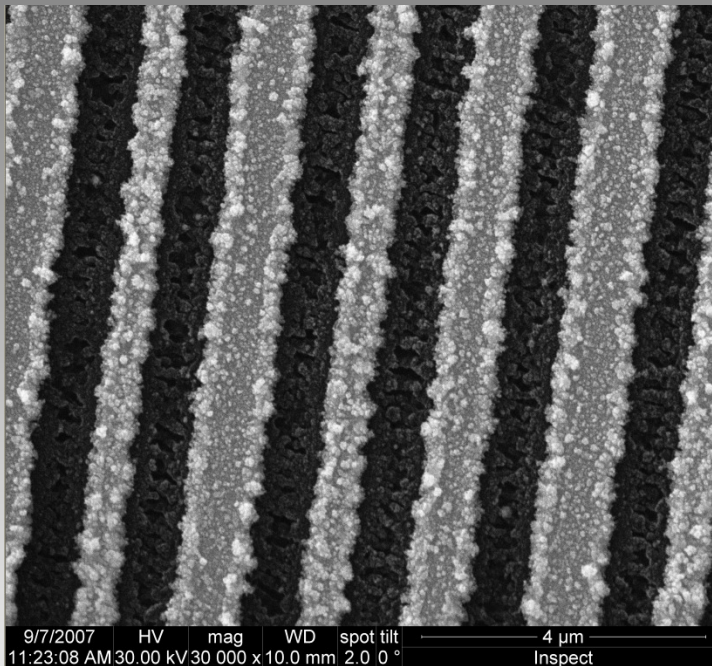
Structures on Co/Cu/Co films  
Grooves width < 500 nm



Laser ablated holes on gold film 100 nm.  
Diameter  $\sim$  830 nm.



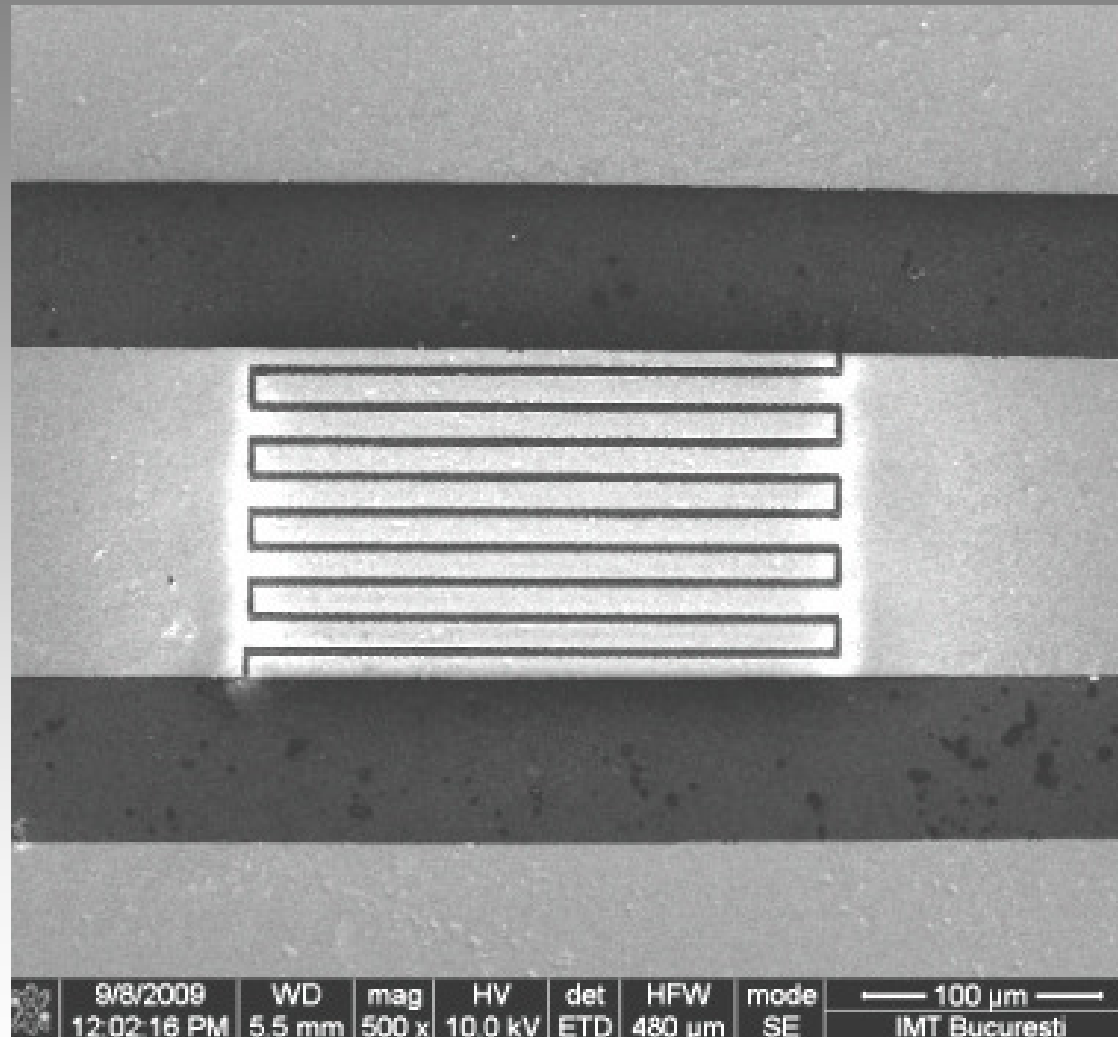
## Laser ablation with sub-micrometer resolution



100 nm gold thin-film deposited on glass. Structures period of 2 μm. Laser wavelength 775 nm, duration 200 fs.

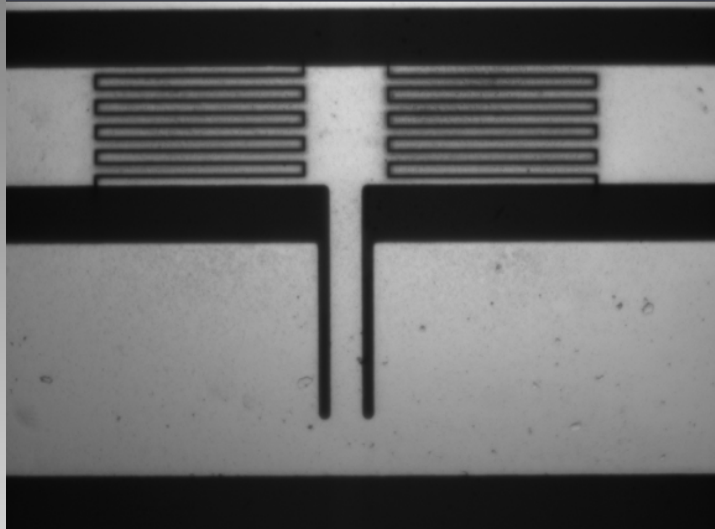
Structures such as interdigital capacitors, electrodes for micro-sensors, etc. can be produced by laser ablation on metallic films, semiconductors, or ceramics usually difficult to be processed by chemical etching.

# Interdigital capacitors fabricated by femtosecond laser

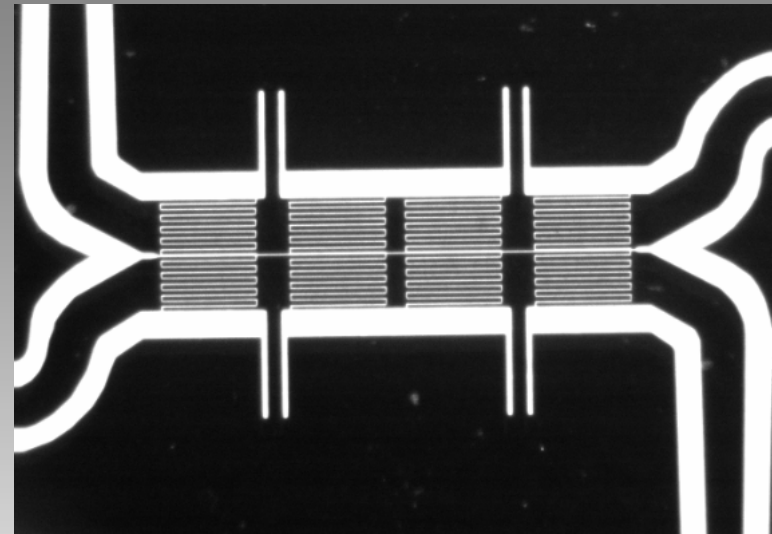


# Microwave devices fabricated by femtosecond laser ablation

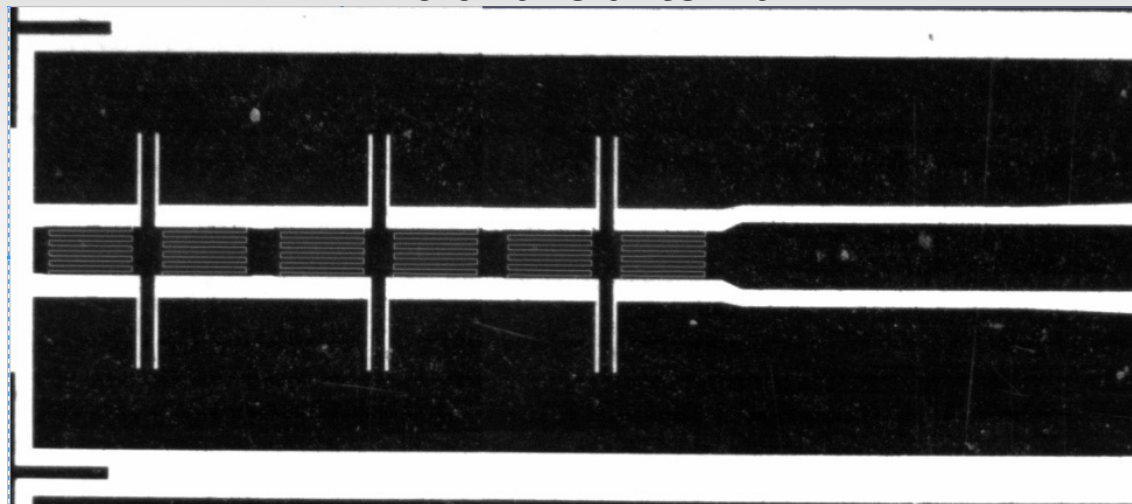
Pass-Band Filter



Directional coupler

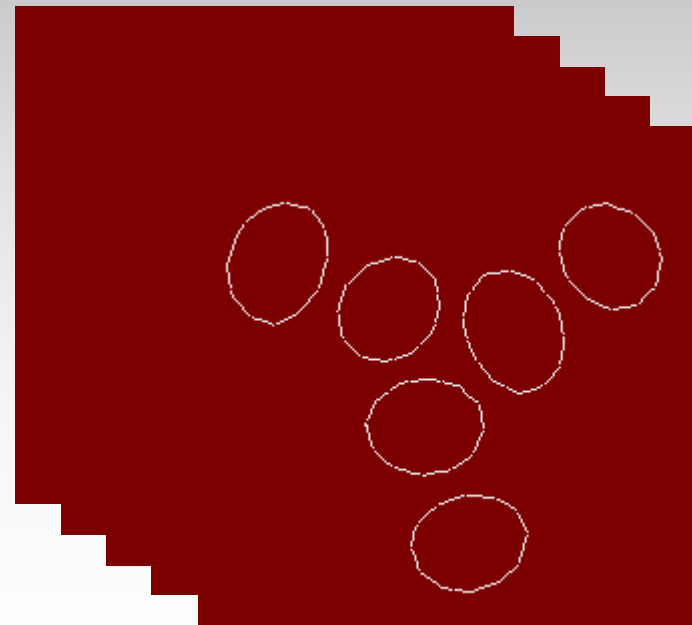
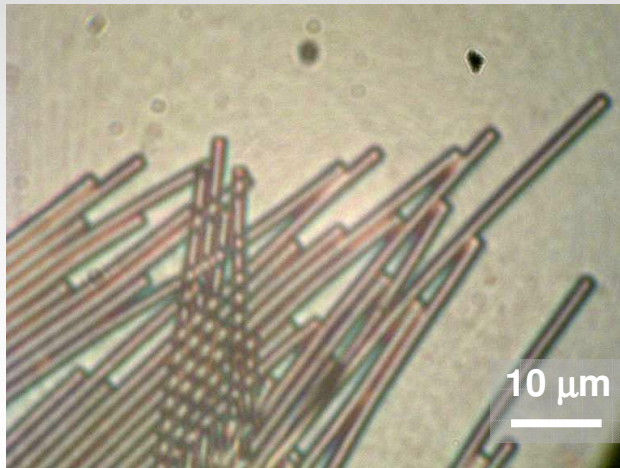
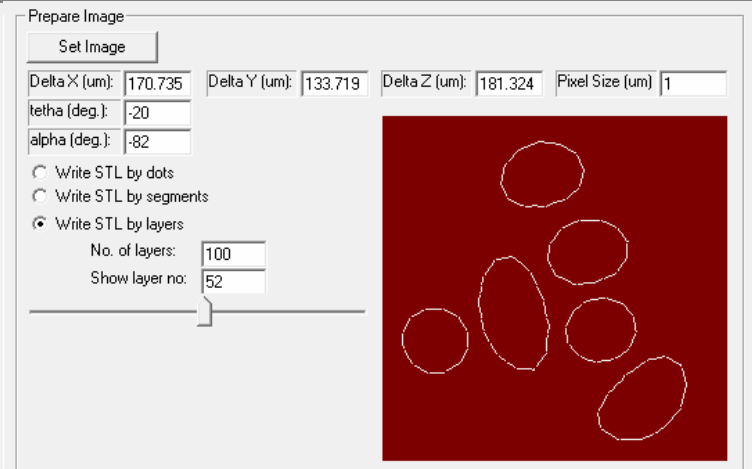
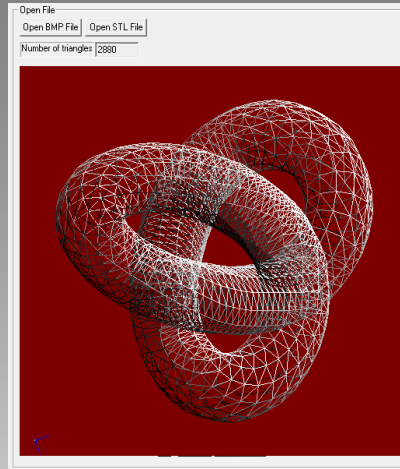
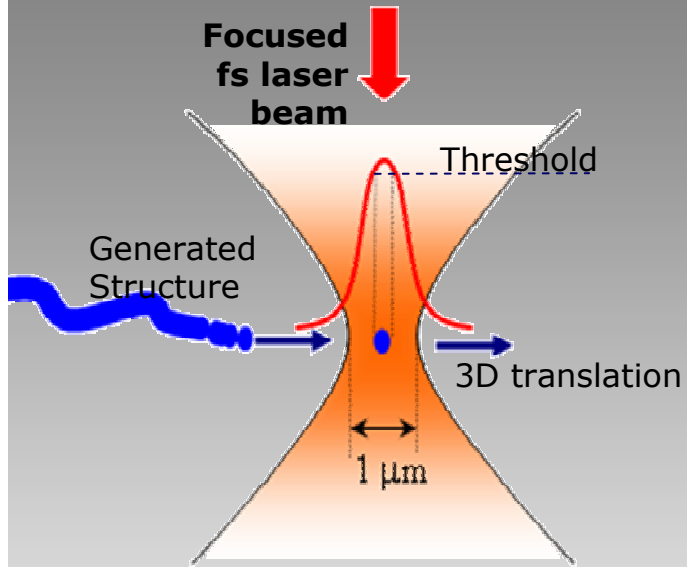


Microwave antenna





# Direct Laser Writing in photopolymers: 3D micro-lithography





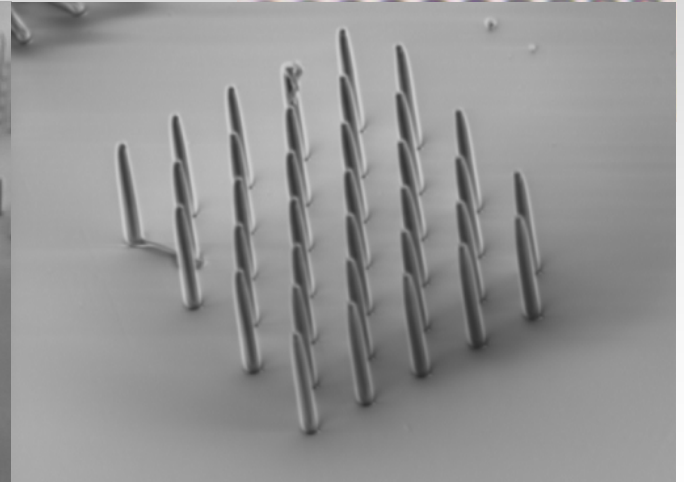
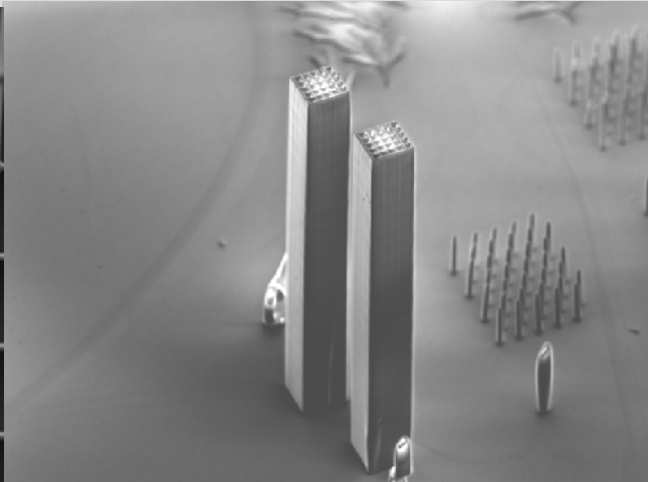
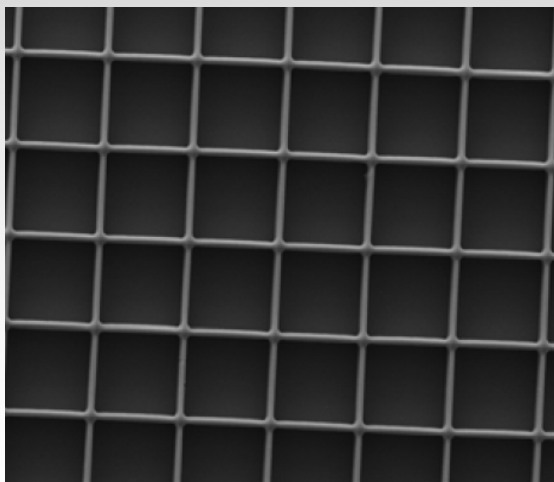
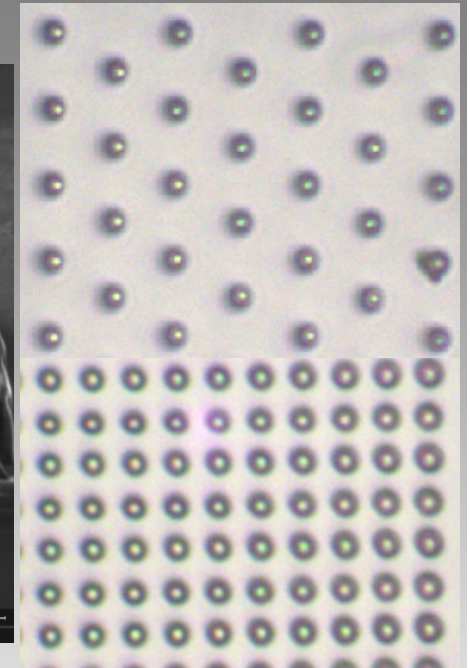
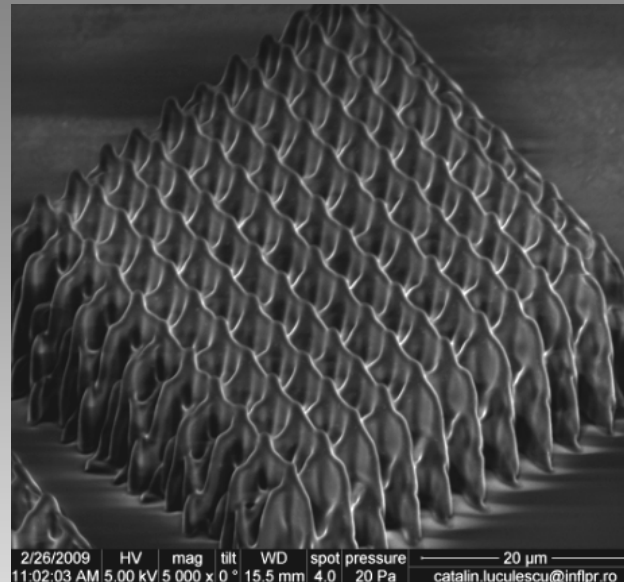
# Microstructures produced by TPP in photopolymers

SU-8, ORMOCERs, ORMOSIL, PMMA

Applications :

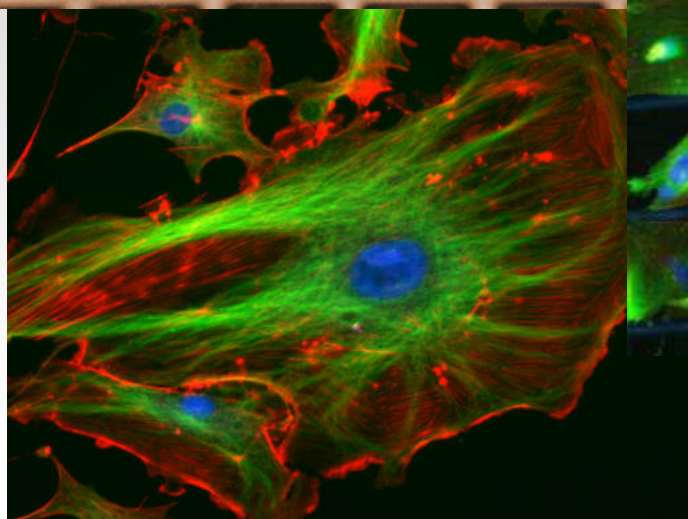
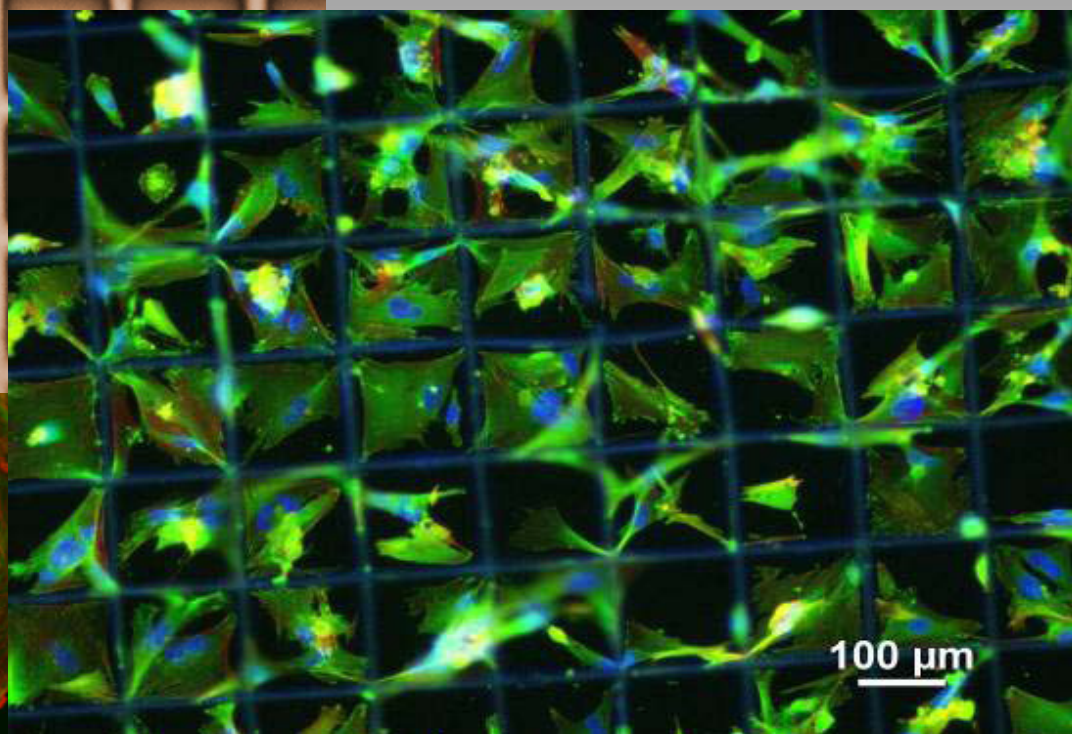
- Micro-optics components: microlenses, photonic crystals, waveguides, optical couplers;
- OCT calibration samples;
- Biocompatible microstructures;
- Micro-fluidics.

*F. Jipa et al., J. Optoe. Adv. Mat. 2010.*



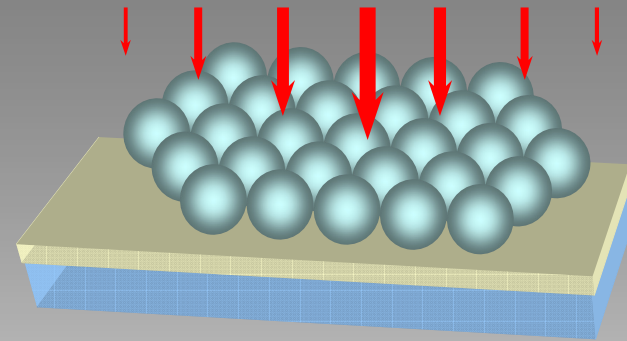
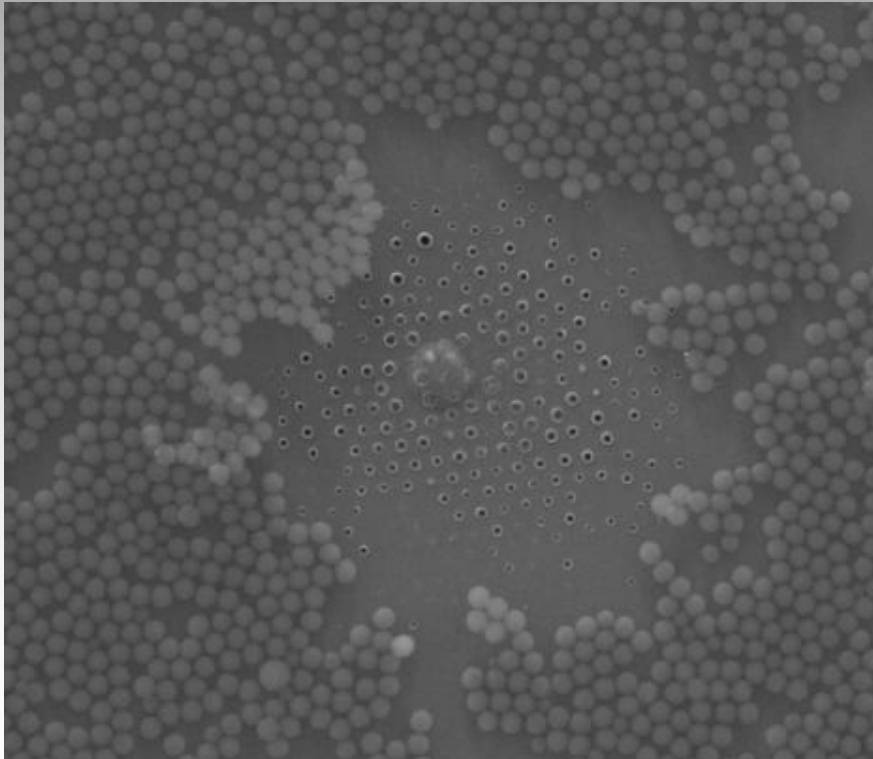
# Applications of 3D TPP in Life Sciences

**Scaffolds for live cells**

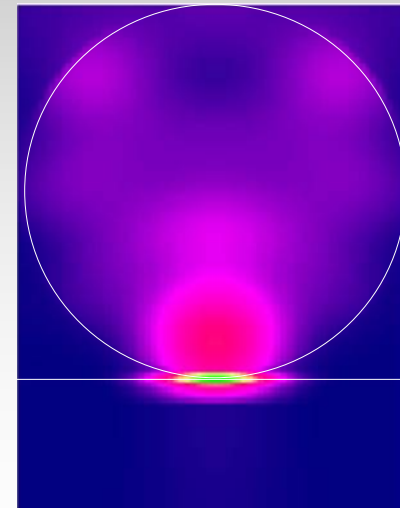


## Near-field laser lithography on colloidal nanoparticles

The field enhancement at the interface of a monolayer of colloidal nanoparticles with a solid substrate produces nanoholes by laser ablation.



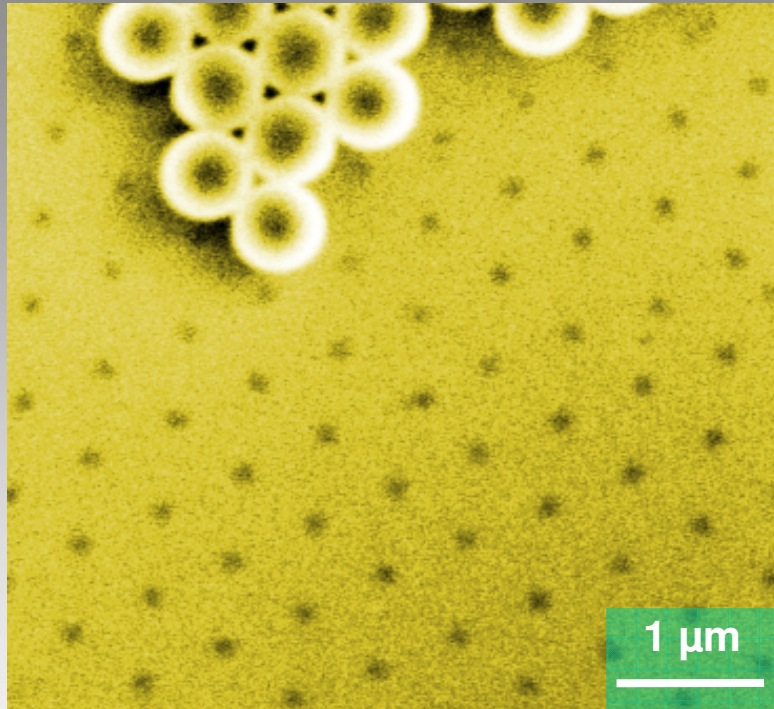
700 nm diameter Silica spheres deposited on glass substrate with an intermediate 50 nm thick gold layer.





# Structures obtained by near-field laser ablation

Glass substrate



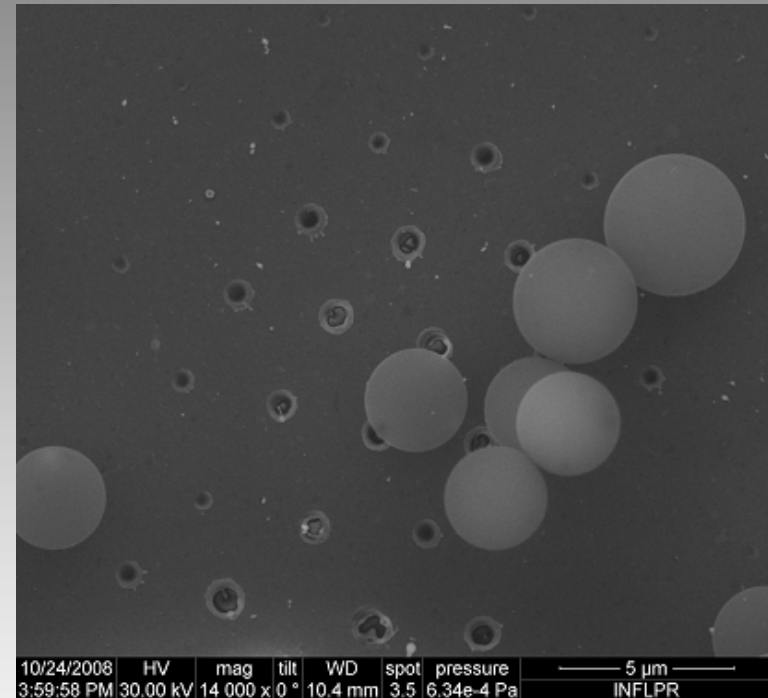
Laser fluence 6 J/cm<sup>2</sup>

Laser **532 nm**, 450 ps

Spheres dimension: **700 nm**

Structure dimension : ~**110 nm**

Gold Film – 50 nm



Laser fluence 0.5 J/cm<sup>2</sup>

Laser **532 nm**, 450 ps

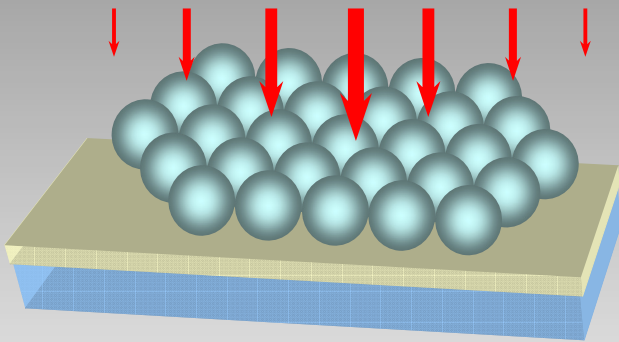
Spheres dimension: **3 μm**

Structure dimension : ~**350 nm**

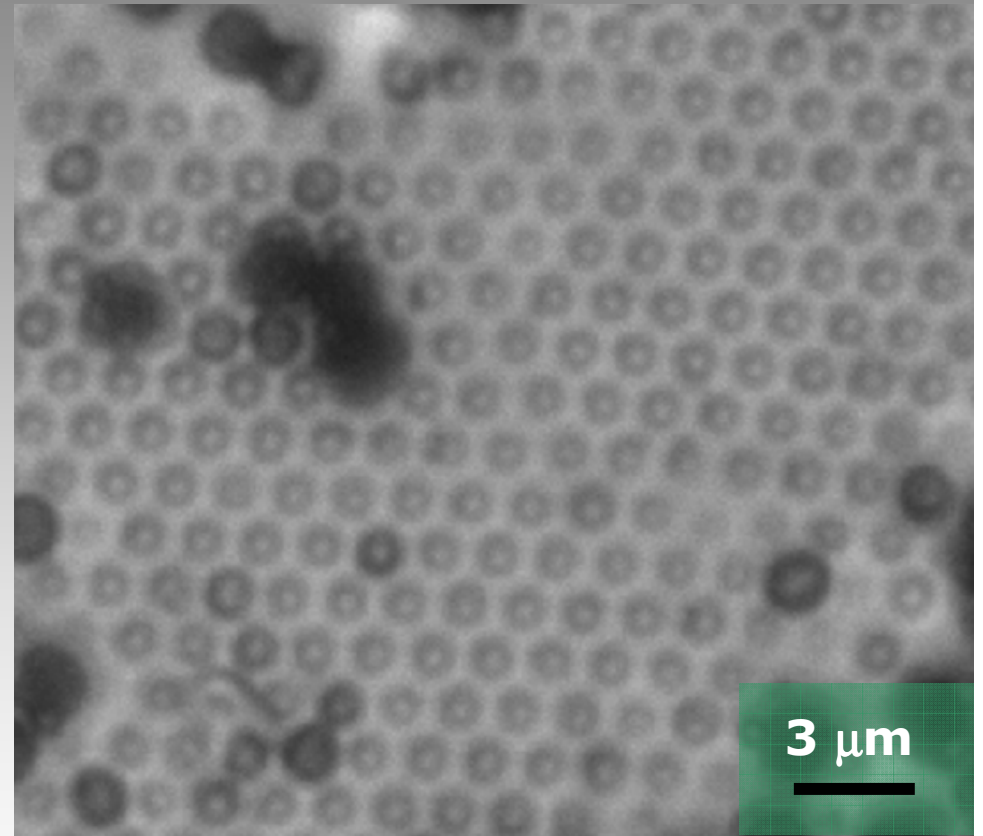
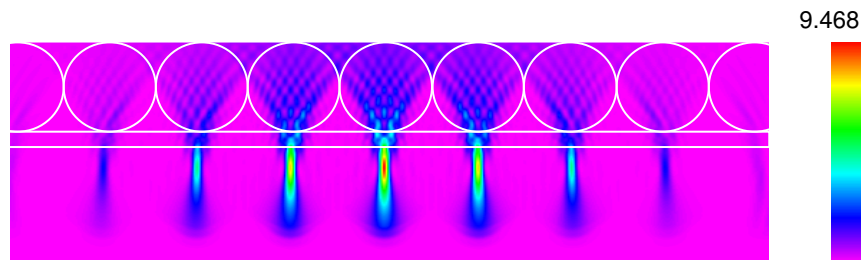
# Parallel processing of photopolymers using colloidal particles

Spheres of polystyrene ( $1.5\ \mu\text{m}$  diameter) are deposited on SU-8 thin film.

The monolayer of PS spheres are irradiated by fs laser beam.



Numerical FDTD simulation shows an optical field enhancement with a factor of 9.

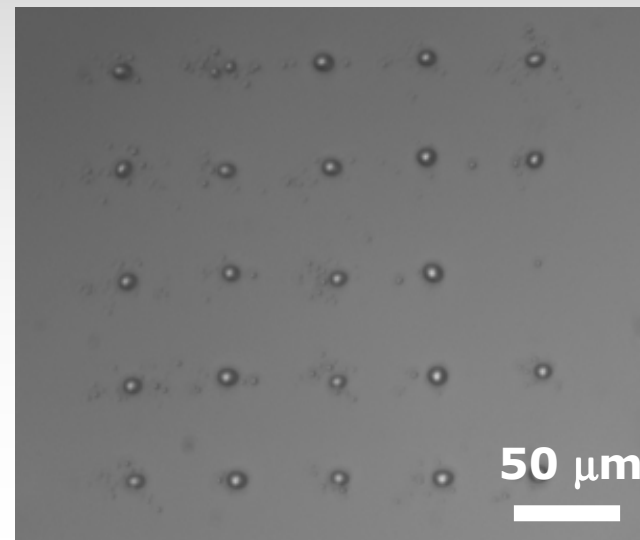
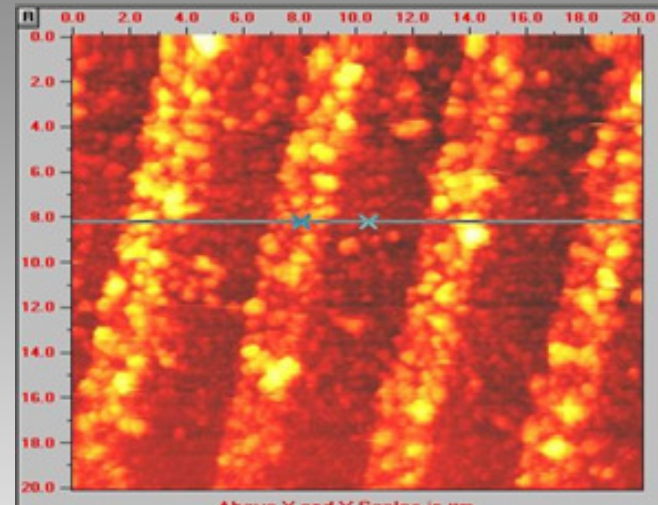
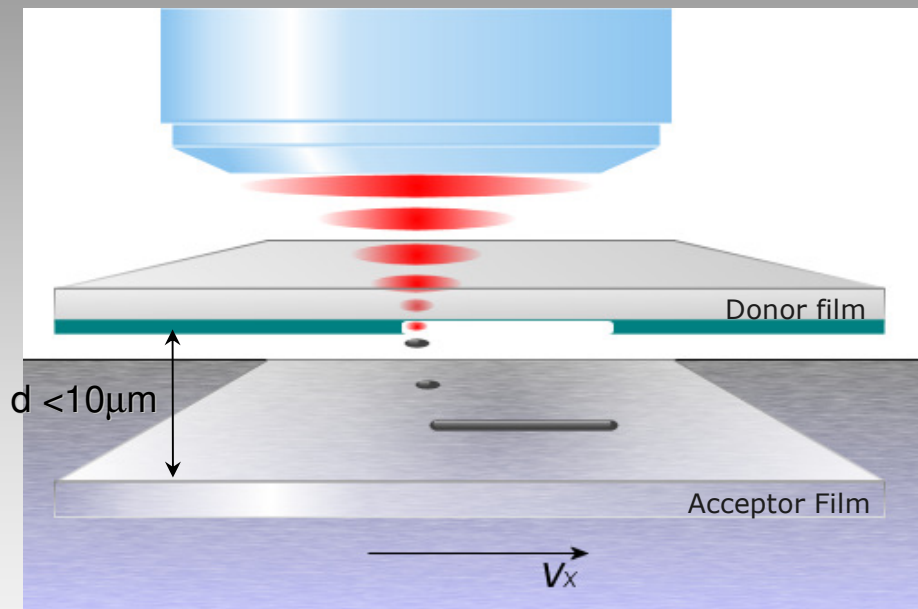


TPP occurs in optical near-field enhancement regime.



# Laser Induced Forward Transfer (LIFT)

Semiconductors, polymers, biological tissues can be transferred by laser from a donor substrate to an acceptor substrate. The size of transferred material is at the order of few microns.

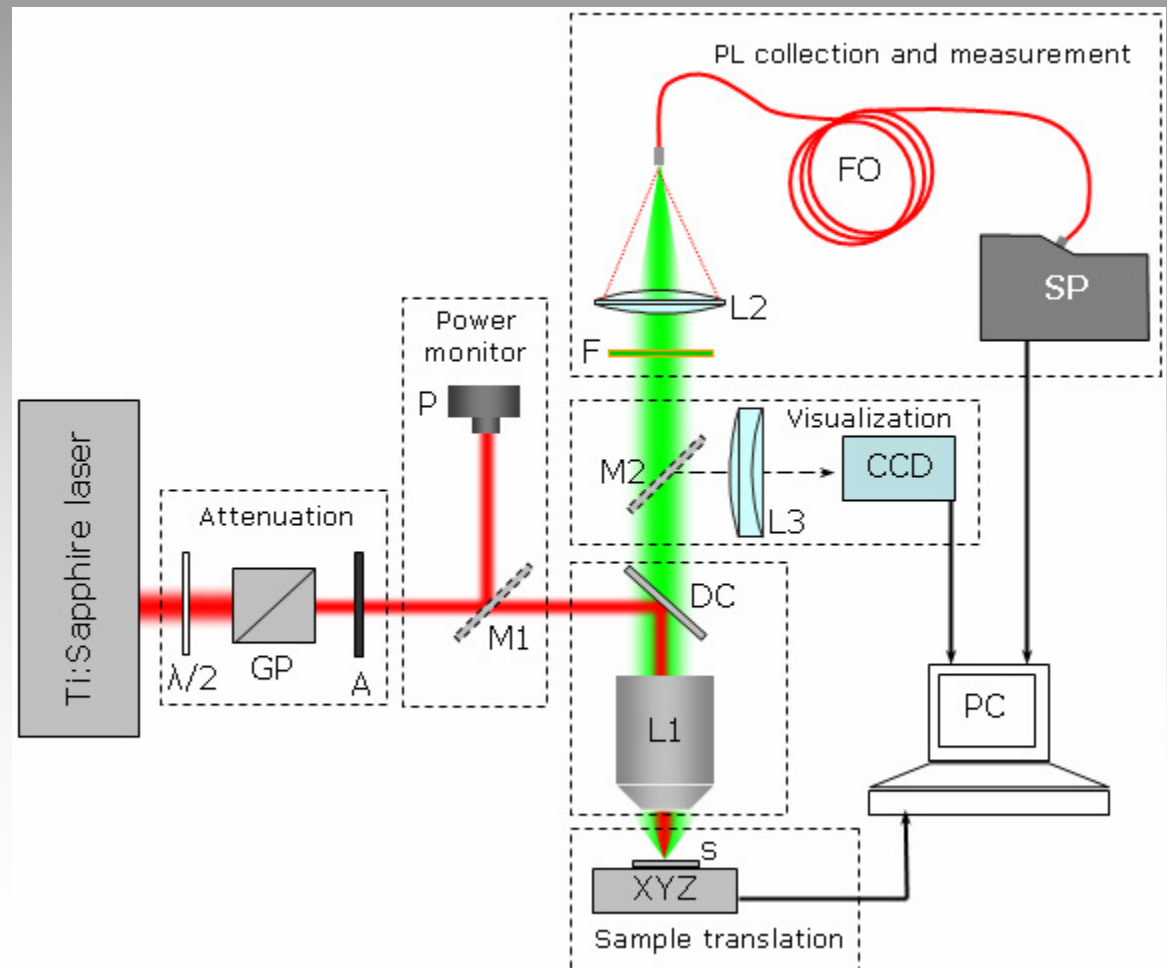
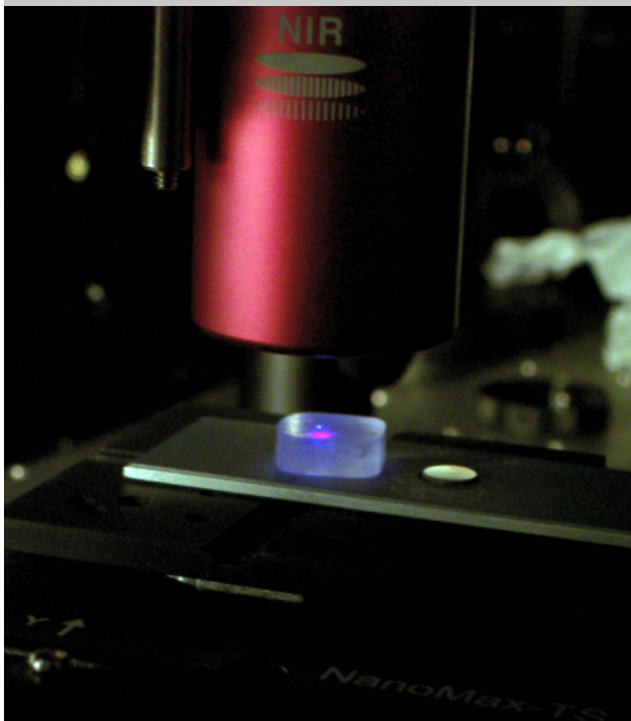


**Droplets of polymers and lines of semiconductor are transferred by laser.**

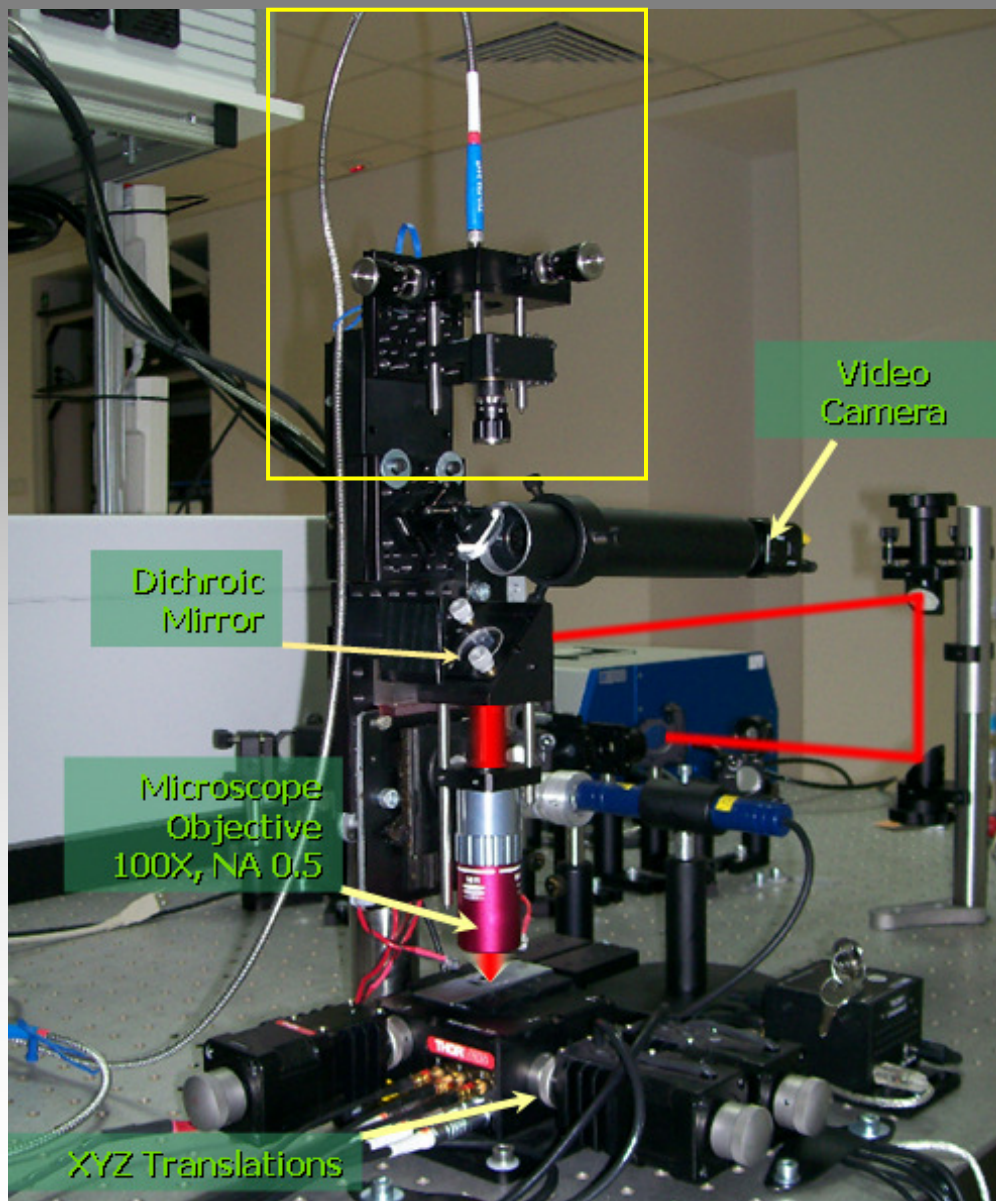
# Two-Photon Excitation Spectroscopy

In the confocal configuration, the DLW workstation is connected through an optical fiber to a spectrometer. A 100  $\mu\text{m}$  optical fiber gives about 5  $\mu\text{m}$  lateral resolution on the sample.

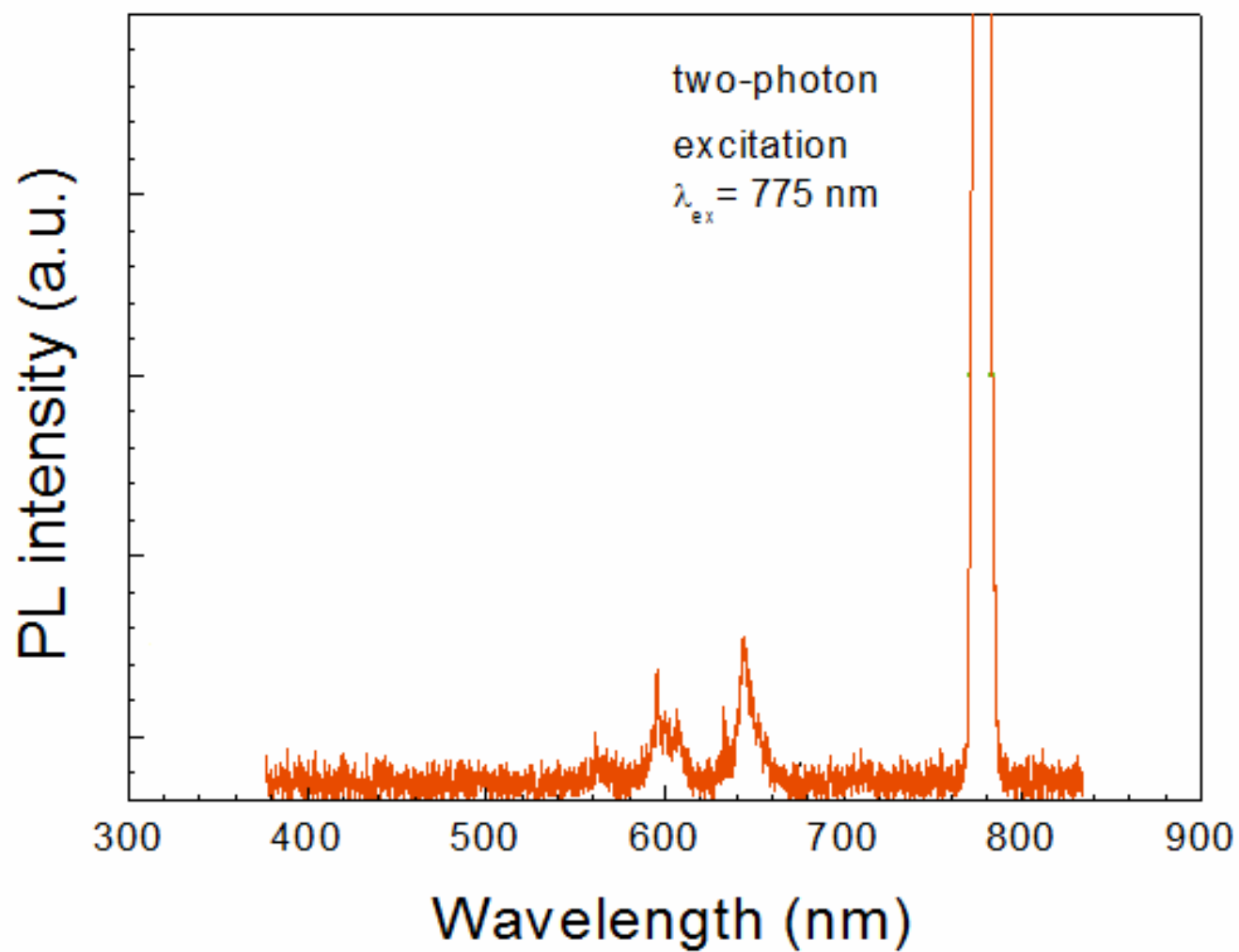
By scanning the sample surface the TPE microscopy image can be recorded.



# Set-up for TPE-Spectroscopy

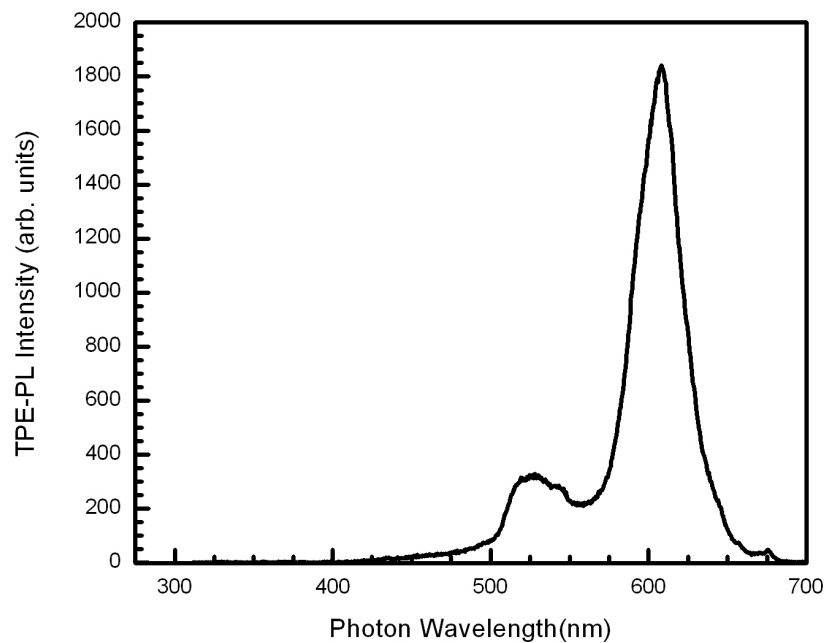


## Typical TPE-PL spectra

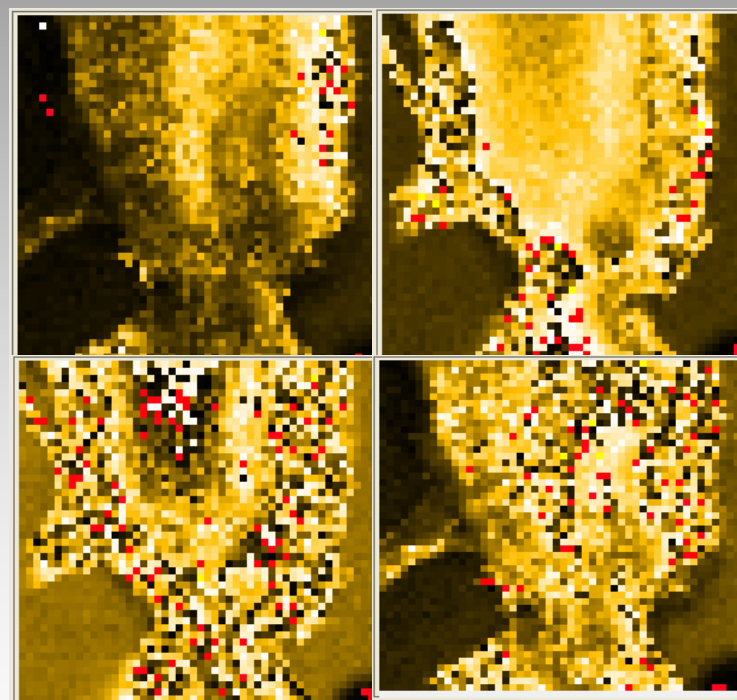


## TPE Microscopy – work in progress

By scanning the sample in XY, a map of TPE-PL intensity can be recorded.



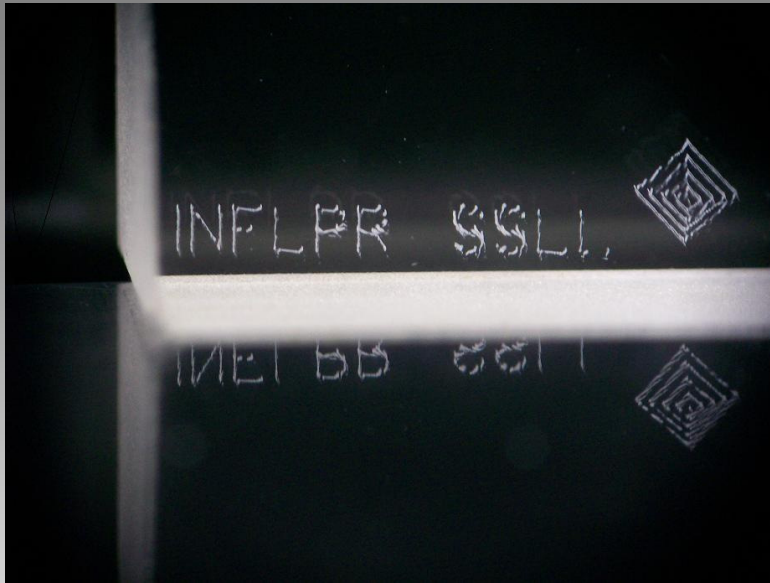
Reconstructed images of a biological sample at different depths inside the sample.





## Conclusions

- ✓ A laser direct writing system was configured for laser processing with femtosecond laser pulses.
- ✓ The laser set-up is compatible with laser processing and characterisation techniques, such as laser ablation, near-field lithography, LIFT, TPP, TPE Spectroscopy.
- ✓ The system allows us to obtain 2D and 3D structures with submicrometric precision.
- ✓ The obtained structures have applications for micro-sensors, micro-optics, metamaterials, micro-fluidics, etc.



## Solid State Lasers Group



<http://ssll.inflpr.ro/>

This work is supported by National Agency of Scientific Research through the projects:  
CNCSIS IDEI268, FEMAT, METALASER, FOTOPOL

**Thank you for your attention!**

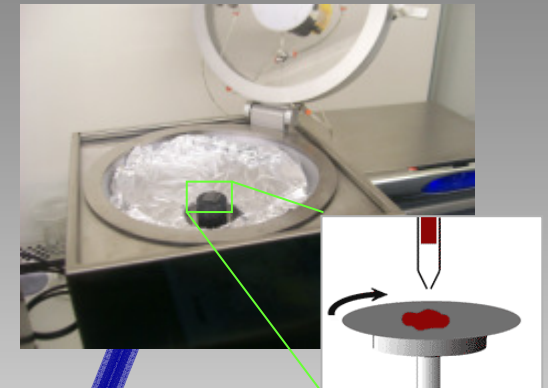
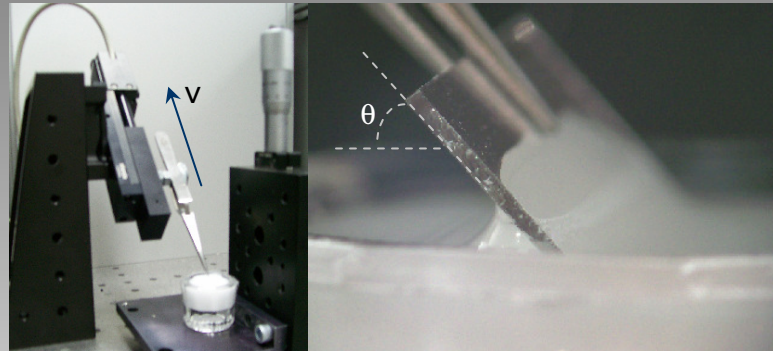
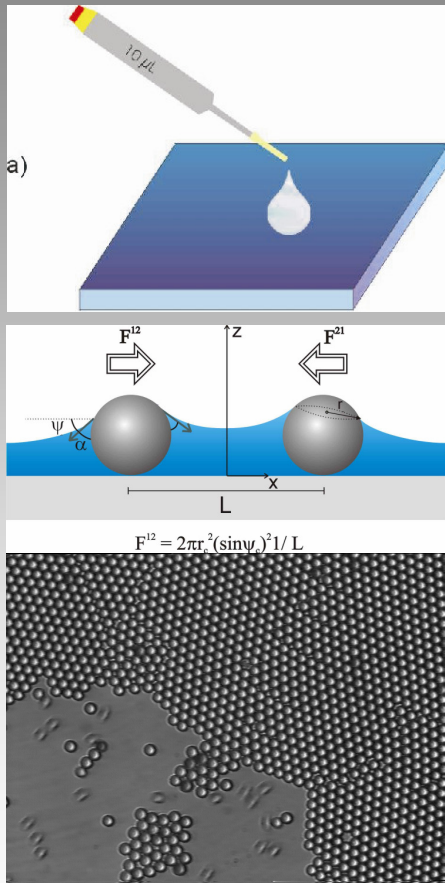






# Self-organization of mono-layers of colloidal nanoparticles

Spin coating



Mono-layers of spheres

